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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/519,084	12/23/2004	Heiji Watanabe	Q85504	7332
23373 SUGHRUE MI	7590 07/09/201 ON, PLLC	EXAMINER		
2100 PENNSY	LVANIA AVENUE, N	CHIU, TSZ K		
	SUITE 800 WASHINGTON, DC 20037			PAPER NUMBER
			2822	
			NOTIFICATION DATE	DELIVERY MODE
			07/09/2010	ELECTRONIC

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Notice of the Office communication was sent electronically on above-indicated "Notification Date" to the following e-mail address(es):

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	Application No.	Applicant(s)				
Office Action Comments	10/519,084	WATANABE ET AL.				
Office Action Summary	Examiner	Art Unit				
	Tsz K. Chiu	2822				
The MAILING DATE of this communication app Period for Reply	pears on the cover sheet with the c	orrespondence address				
A SHORTENED STATUTORY PERIOD FOR REPL' WHICHEVER IS LONGER, FROM THE MAILING D. - Extensions of time may be available under the provisions of 37 CFR 1.1 after SIX (6) MONTHS from the mailing date of this communication. - If NO period for reply is specified above, the maximum statutory period of Failure to reply within the set or extended period for reply will, by statute Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be time will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	lely filed the mailing date of this communication. (35 U.S.C. § 133).				
Status						
1)⊠ Responsive to communication(s) filed on <u>18 F</u>	ebruary 2010					
	action is non-final.					
	,—					
•	closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.					
Disposition of Claims	2. parto quajro, 1000 0.2. 11, 10					
· <u> </u>						
	Claim(s) <u>21-40</u> is/are pending in the application.					
4a) Of the above claim(s) is/are withdrawn from consideration.						
5)⊠ Claim(s) <u>21-36 and 40</u> is/are allowed.						
· · · · · · · · · · · · · · · · · · ·	6) Claim(s) 37-39 is/are rejected.					
7) Claim(s) is/are objected to.						
8) Claim(s) are subject to restriction and/or election requirement.						
Application Papers						
9)☐ The specification is objected to by the Examiner.						
10)☐ The drawing(s) filed on is/are: a)☐ accepted or b)☐ objected to by the Examiner.						
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).						
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).						
11)☐ The oath or declaration is objected to by the Ex	caminer. Note the attached Office	Action or form PTO-152.				
Priority under 35 U.S.C. § 119						
12)⊠ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a)⊠ All b)□ Some * c)□ None of:						
1.⊠ Certified copies of the priority documents have been received.						
2. Certified copies of the priority documents have been received in Application No						
3. Copies of the certified copies of the priority documents have been received in this National Stage						
application from the International Bureau (PCT Rule 17.2(a)).						
* See the attached detailed Office action for a list of the certified copies not received.						
Attachment(s)						
1) Notice of References Cited (PTO-892)	4) Interview Summary					
2) Notice of Draftsperson's Patent Drawing Review (PTO-948) Paper No(s)/Mail Date 3) Information Disclosure Statement(s) (PTO/SB/08) Notice of Informal Patent Application						
3) Information Disclosure Statement(s) (PTO/SB/08) Paper No(s)/Mail Date 5) Notice of Informal Patent Application 6) Other:						

Application/Control Number: 10/519,084 Page 2

Art Unit: 2822

DETAILED ACTION

Response to Arguments

Applicant's arguments, see arguments/remark, filed 2/18/10, with respect to the rejection(s) of claim(s) 37-39 under 35 USC 102(e) have been fully considered and are persuasive. Therefore, the rejection has been withdrawn. However, upon further consideration, a new ground(s) of rejection is made in view of Harada (20020195643).

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

Claims 37-39 are rejected under 35 U.S.C. 102(e) as being anticipated by Harada (20020195643).

With respect to claim 37, Harada discloses a semiconductor device stacked a gate insulating film (11, for example figure. 1) and a gate electrode (12, for example figure. 1) stacked in this order on a silicon substrate (10, for example figure. 1); wherein said gate insulating film (11, for example figure. 1) has a layered structure having, from the silicon substrate side (10, for example figure. 1), a first silicon oxide film, a metal oxide film or a metal silicate film (11b, For example Fig. 1) and a second silicon oxide film (11a, For example Fig. 1); and

Art Unit: 2822

only the second silicon oxide film (11a, For example Fig. 1) has a structure in which nitrogen is introduced into silicon oxide.

With respect to claim 38, Harada discloses, wherein said silicon substrate (10, for example figure. 1) and said gate insulating film (11, for example figure. 1) are in contact with each other, and said gate insulating film (11, for example figure. 1) and a gate electrode (12, for example figure. 1) are in contact with each other; and said gate electrode (12, For example Fig. 1) is made of either a polysilicon or a polysilicon germanium conductive film (paragraph 75).

With respect to claim 39, Harada discloses the gate insulating film (11, For example Fig. 1) contains at least one type selected from the group consisting of Zr, Hf, Ta, A1, Ti, Nb, Sc, Y, La, Ce, Pr, Nd, Sm, Eu, Gd, Tb. Dy, Ho, Er, Tm, Yb and Lu (paragraph 75).

Allowable Subject Matter

Claims 21-36 and 40 are allowed.

The following is a statement of reasons for the indication of allowable subject matter:

Claim 21 is allowable over the reference of record because none of these references disclose or can be combined to yield the claimed invention of a semiconductor device stacked a gate with gate insulating film comprises a nitrogen containing high-dielectric-constant insulating film a position at which the nitrogen concentration in said nitrogen containing high-dielectric-constant insulating film reaches

a maximum in the direction of the film thickness is present in a region at a distance from the silicon substrate.

Claim 29 is allowable over the reference of record because none of these references disclose or can be combined to yield the claimed invention of a semiconductor device stacked a gate with gate insulating film comprises a nitrogen containing high-dielectric-constant insulating film a position at which the nitrogen concentration in said nitrogen containing high-dielectric-constant insulating film selectively bonds with a silicon atom in metal silicate.

Claim 34 is allowable over the reference of record because none of these references disclose or can be combined to yield the claimed invention of a semiconductor device stacked a gate with gate insulating film comprises a nitrogen containing high-dielectric-constant insulating film nitrogen is introduced only into a region lying between the position at which the silicon concentration has the minimum value and said gate electrode side interface.

Claim 40 is allowable over the reference of record because none of these references disclose or can be combined to yield the claimed invention of a semiconductor device stacked a gate with gate insulating film comprises a nitrogen containing high-dielectric-constant insulating film a position at which the nitrogen concentration in said gate insulating film reaches a maximum in the direction of the film thickness is present in a region at a distance from the silicon substrate.

Application/Control Number: 10/519,084 Page 5

Art Unit: 2822

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Tsz K. Chiu whose telephone number is 571-272-8656. The examiner can normally be reached on 0800 to 1700.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Zandra V. Smith can be reached on 571-272-2429. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/Zandra V. Smith/ Supervisory Patent Examiner, Art Unit 2822

/Tsz K Chiu/ Examiner, Art Unit 2822